

L Number	Hits	Search Text	DB	Time stamp
1	170	piezoelectric and ((metal\$3 adj layer) same titanium)	USPAT; JPO; DERWENT	2004/04/29 11:48
2	18	(piezoelectric and ((metal\$3 adj layer) same titanium)) and SAW	USPAT; JPO; DERWENT	2004/04/29 12:49
3	1	"5909156".PN.	USPAT	2004/04/29 11:43
4	5	("4445066" "4775814" "5144185" "5773917" "5909156").PN.	USPAT	2004/04/29 11:46
5	0	((("4445066" "4775814" "5144185" "5773917" "5909156").PN.) and ((metal\$3 adj layer) same titanium)	USPAT; JPO; DERWENT	2004/04/29 11:48
6	2	((("4445066" "4775814" "5144185" "5773917" "5909156").PN.) and piezoelectric and titanium	USPAT; JPO; DERWENT	2004/04/29 11:48
7	1	(US-6259185-\$.did.	USPAT	2004/04/29 12:43
9	0	((US-6259185-\$.did.) and (shear same wave)	USPAT; JPO; DERWENT	2004/04/29 12:44
10	0	((US-6259185-\$.did.) and shear	USPAT; JPO; DERWENT	2004/04/29 12:44
11	1	((US-6259185-\$.did.) and wave	USPAT; JPO; DERWENT	2004/04/29 12:48
12	0	((US-6259185-\$.did.) and horizon\$3	USPAT; JPO; DERWENT	2004/04/29 12:48
8	3	(piezoelectric and ((metal\$3 adj layer) same titanium)) and (shear same wave)	USPAT; JPO; DERWENT	2004/04/29 12:49
13	71	shear adj horizontal adj wave	USPAT; JPO; DERWENT	2004/04/29 12:57
15	3	(shear adj horizontal adj wave) same SAW	USPAT; JPO; DERWENT	2004/04/29 12:57
14	22	(shear adj horizontal adj wave) and SAW	USPAT; JPO; DERWENT	2004/04/29 12:51
16	5390	surface adj acoustic adj wave adj device	USPAT; JPO; DERWENT	2004/04/29 12:58
17	17	(shear adj horizontal adj wave) and (surface adj acoustic adj wave adj device)	USPAT; JPO; DERWENT	2004/04/29 12:59
18	0	(piezoelectric and ((metal\$3 adj layer) same titanium)) and ((shear adj horizontal adj wave) and (surface adj acoustic adj wave adj device))	USPAT; JPO; DERWENT	2004/04/29 12:59
19	17	((shear adj horizontal adj wave) and (surface adj acoustic adj wave adj device)) and @ay<19990902	USPAT; JPO; DERWENT	2004/04/29 12:59
20	6	((shear adj horizontal adj wave) and (surface adj acoustic adj wave adj device)) and @ad<19990902	USPAT; JPO; DERWENT	2004/04/29 13:02
21	6	("5773917" "5844347" "5847486" "5854527" "5905325" "5909156").PN.	USPAT	2004/04/29 13:01
22	0	(shear adj horizontal adj wave) and (("5773917" "5844347" "5847486" "5854527" "5905325" "5909156").PN.)	USPAT; JPO; DERWENT	2004/04/29 13:02
-	125915	sputtering	USPAT; JPO; DERWENT	2004/01/09 09:04
-	0	sputtering with (iner adj gas) with nitrogen	USPAT; JPO; DERWENT	2004/01/08 16:23

-	369	sputtering with (inert adj gas) with nitrogen	USPAT; JPO; DERWENT	2004/01/08 16:24
-	4	(sputtering with (inert adj gas) with nitrogen) and saw	USPAT; JPO; DERWENT	2004/01/08 16:24
-	7	sputtering with (inert adj gas) with (nitrogen or argon) and SAW	USPAT; JPO; DERWENT	2004/01/08 16:32
-	1790	204/192.15.ccls.	USPAT; JPO; DERWENT	2004/01/08 16:32
-	57285	tantalum	USPAT; JPO; DERWENT	2004/01/08 16:32
-	313	204/192.15.ccls. and tantalum	USPAT; JPO; DERWENT	2004/01/08 16:32
-	0	a-tantalum	USPAT; JPO; DERWENT	2004/01/08 16:32
-	1	a-tantalum	USPAT; JPO; DERWENT	2004/01/08 16:33
-	81	alpha adj tantalum	USPAT; JPO; DERWENT	2004/01/08 16:48
-	9	204/192.15.ccls. and (alpha adj tantalum)	USPAT; JPO; DERWENT	2004/01/08 16:33
-	10	sputtering with (alpha adj tantalum) with (nitrogen or argon)	USPAT; JPO; DERWENT	2004/01/09 09:49
-	5	("4340834" "5221449" "5281485" "5847486" "5850167").PN.	USPAT	2004/01/08 16:34
-	1	IDT with (alpha adj tantalum)	USPAT; JPO; DERWENT	2004/01/08 16:42
-	3	interdigital with (alpha adj tantalum)	USPAT; JPO; DERWENT	2004/01/08 16:42
-	26	electrode with (alpha adj tantalum)	USPAT; JPO; DERWENT	2004/01/08 16:40
-	6	("4251326" "5162690" "5221449" "5274482" "6218763" "6127769").PN.	USPAT	2004/01/08 16:40
-	1	((("4251326" "5162690" "5221449" "5274482" "6218763" "6127769").PN.) and IDT	USPAT; JPO; DERWENT	2004/01/08 16:41
-	0	((("4251326" "5162690" "5221449" "5274482" "6218763" "6127769").PN.) and IDT) and (alpha adj tantalum)	USPAT; JPO; DERWENT	2004/01/08 16:42
-	4	(interdigital with tantalum) and (alpha adj tantalum)	USPAT; JPO; DERWENT	2004/01/08 16:42
-	15	interdigital with tantalum	USPAT; JPO; DERWENT	2004/01/08 16:43
-	5	29/592.1,594,609.1.ccls. and IDT	USPAT; JPO; DERWENT	2004/01/08 16:46
-	55	29/\$.ccls. and IDT	USPAT; JPO; DERWENT	2004/01/08 16:46
-	13	29/592.1,594,609.1.ccls. and interdigital	USPAT; JPO; DERWENT	2004/01/08 16:46

-	143	29/\$.ccls. and interdigital	USPAT; JPO; DERWENT	2004/01/08 16:46
-	0	(alpha adj tantalum) and (29/\$.ccls. and interdigital)	USPAT; JPO; DERWENT	2004/01/08 16:46
-	4	(alpha adj tantalum) and interdigit\$2	USPAT; JPO; DERWENT	2004/01/08 16:48
-	111651	low with resist\$3	USPAT; JPO; DERWENT	2004/01/09 09:04
-	4324	low adj resist\$3	USPAT; JPO; DERWENT	2004/01/09 09:05
-	12280	interdigital wth taltalum	USPAT; JPO; DERWENT	2004/01/09 09:06
-	11	(low adj resist\$3) and (interdigital wth taltalum)	USPAT; JPO; DERWENT	2004/01/09 09:05
-	1	(interdigital wth taltalum) same (low adj resist\$3)	USPAT; JPO; DERWENT	2004/01/09 09:06
-	42	(interdigital wth tantalum) same (low adj resist\$3)	USPAT; JPO; DERWENT	2004/01/09 10:21
-	0	(interdigital near tantalum) same (low adj resist\$3)	USPAT; JPO; DERWENT	2004/01/09 09:08
-	0	(interdigital same tantalum) same (low adj resist\$3)	USPAT; JPO; DERWENT	2004/01/09 09:08
-	0	(interdigital with tantalum) same (low adj resist\$3)	USPAT; JPO; DERWENT	2004/01/09 09:09
-	0	(tantalum same (low adj resist\$3)) and interdigital	USPAT; JPO; DERWENT	2004/01/09 09:41
-	41	tantalum same (low adj resist\$3)	USPAT; JPO; DERWENT	2004/01/09 09:35
-	0	(alpha adj tantalum) same (low adj resist\$3)	USPAT; JPO; DERWENT	2004/01/09 10:24
-	2	((alpha adj tantalum) same ((low or reduce\$1) adj resist\$5)) and interdigital	USPAT; JPO; DERWENT	2004/01/09 09:44
-	17	(alpha adj tantalum) same ((low or reduce\$1) adj resist\$5)	USPAT; JPO; DERWENT	2004/01/09 09:44
-	1	((alpha adj tantalum) same ((low or reduce\$1) adj resist\$5)) and SAW	USPAT; JPO; DERWENT	2004/01/09 09:44
-	852	(interdigital wth tantalum) same (low adj resist\$5)	USPAT; JPO; DERWENT	2004/01/09 09:48
-	327	sputtering with (tantalum) with (nitrogen or argon)	USPAT; JPO; DERWENT	2004/01/15 09:12
-	30	((interdigital wth tantalum) same (low adj resist\$5)) and (sputtering with (tantalum) with (nitrogen or argon))	USPAT; JPO; DERWENT	2004/01/09 10:07
-	4793	sputtering same (distance or space or distance) same (target or substrate)	USPAT; JPO; DERWENT	2004/01/09 10:08

-	4793	sputtering same (space or distance) same (target or substrate)	USPAT; JPO; DERWENT	2004/01/09 10:08
-	57	(sputtering with tantalum) same (space or distance) same (target or substrate)	USPAT; JPO; DERWENT	2004/01/12 09:12
-	36	(sputtering with tantalum) same (pressure) same (power) same temperature	USPAT; JPO; DERWENT	2004/01/09 10:17
-	0	(interdigital with tantalum) same (low adj resist\$3) same reflector	USPAT; JPO; DERWENT	2004/01/09 10:25
-	1055	(interdigital with tantalum) same reflector	USPAT; JPO; DERWENT	2004/01/09 10:23
-	436	((interdigital with tantalum) same reflector) and saw	USPAT; JPO; DERWENT	2004/01/09 10:22
-	1083	(reflector with tantalum) same SAW	USPAT; JPO; DERWENT	2004/01/09 10:24
-	81	alpha adj tantalum	USPAT; JPO; DERWENT	2004/01/09 10:24
-	1	((reflector with tantalum) same SAW) and (alpha adj tantalum)	USPAT; JPO; DERWENT	2004/01/09 10:24
-	1	(alpha adj tantalum) with reflector	USPAT; JPO; DERWENT	2004/01/09 10:24
-	1055	(interdigital with tantalum) same reflector	USPAT; JPO; DERWENT	2004/01/09 10:25
-	1	(interdigital with tantalum) same (low adj resist\$5) same reflector	USPAT; JPO; DERWENT	2004/01/09 10:25
-	0	tantalum same (low adj resist\$5) same reflector	USPAT; JPO; DERWENT	2004/01/09 10:26
-	7	(tantalum same reflector) and saw	USPAT; JPO; DERWENT	2004/01/09 10:26
-	142	tantalum same reflector	USPAT; JPO; DERWENT	2004/01/09 10:27
-	9	(sputtering with tantalum) same (space or distance) same (target or substrate) same thickness	USPAT; JPO; DERWENT	2004/01/12 09:39
-	4	saw and (reflector\$1 with tantalum)	USPAT; JPO; DERWENT	2004/01/12 09:40
-	7	saw and (reflector\$1 same tantalum)	USPAT; JPO; DERWENT	2004/01/12 09:42
-	5	IDT and (reflector\$1 same tantalum)	USPAT; JPO; DERWENT	2004/01/12 09:42
-	15	(US-6144057-\$ or US-5281485-\$ or US-5221449-\$ or US-6226171-\$ or US-4410867-\$ or US-5850167-\$ or US-5140403-\$ or US-6088462-\$ or US-6110598-\$ or US-5281554-\$ or US-6375312-\$ or US-5714268-\$ or US-6191031-\$ or US-6154105-\$).did. or (JP-04186815-\$).did.	USPAT; JPO	2004/01/15 08:51
-	3	((US-6144057-\$ or US-5281485-\$ or US-5221449-\$ or US-6226171-\$ or US-4410867-\$ or US-5850167-\$ or US-5140403-\$ or US-6088462-\$ or US-6110598-\$ or US-5281554-\$ or US-6375312-\$ or US-5714268-\$ or US-6191031-\$ or US-6154105-\$).did. or (JP-04186815-\$).did.) and piezoelectric	USPAT; JPO; DERWENT	2004/01/15 09:34

-	18	sputtering with (alpha adj tantalum)	USPAT; JPO; DERWENT	2004/01/15 09:00
-	3	piezoelectric with (alpha adj tantalum)	USPAT; JPO; DERWENT	2004/01/15 09:00
-	186	(vapor daj deposition) with (tantalum) with (nitrogen or argon)	USPAT; JPO; DERWENT	2004/01/15 09:14
-	2	(vapor daj deposition) with (alpha adj tantalum) with (nitrogen or argon)	USPAT; JPO; DERWENT	2004/01/15 09:13
-	699640	vapor daj deposition	USPAT; JPO; DERWENT	2004/01/15 09:13
-	1	(vapor adj deposition) with (alpha adj tantalum) with (nitrogen or argon)	USPAT; JPO; DERWENT	2004/01/15 09:14
-	58	(vapor adj deposition) with (tantalum) with (nitrogen or argon)	USPAT; JPO; DERWENT	2004/01/15 09:14
-	0	(vapor adj deposition) with metal with piezoelectric with (nitrogen or argon)	USPAT; JPO; DERWENT	2004/01/15 09:15
-	12	((vapor adj deposition) with metal with piezoelectric) and saw	USPAT; JPO; DERWENT	2004/01/15 09:15
-	1	((US-6144057-\$ or US-5281485-\$ or US-5221449-\$ or US-6226171-\$ or US-4410867-\$ or US-5850167-\$ or US-5140403-\$ or US-6088462-\$ or US-6110598-\$ or US-5281554-\$ or US-6375312-\$ or US-5714268-\$ or US-6191031-\$ or US-6154105-\$).did. or (JP-04186815-\$).did.) and (vapor adj deposition)	USPAT; JPO; DERWENT	2004/01/15 09:17
-	93	(vapor adj deposition) with metal with piezoelectric	USPAT; JPO; DERWENT	2004/01/15 09:19
-	8	((US-6144057-\$ or US-5281485-\$ or US-5221449-\$ or US-6226171-\$ or US-4410867-\$ or US-5850167-\$ or US-5140403-\$ or US-6088462-\$ or US-6110598-\$ or US-5281554-\$ or US-6375312-\$ or US-5714268-\$ or US-6191031-\$ or US-6154105-\$).did. or (JP-04186815-\$).did.) and tungsten	USPAT; JPO; DERWENT	2004/01/15 09:36
-	6	((US-6144057-\$ or US-5281485-\$ or US-5221449-\$ or US-6226171-\$ or US-4410867-\$ or US-5850167-\$ or US-5140403-\$ or US-6088462-\$ or US-6110598-\$ or US-5281554-\$ or US-6375312-\$ or US-5714268-\$ or US-6191031-\$ or US-6154105-\$).did. or (JP-04186815-\$).did.) and (tungsten with tantalum)	USPAT; JPO; DERWENT	2004/01/15 09:39
-	2	((US-6144057-\$ or US-5281485-\$ or US-5221449-\$ or US-6226171-\$ or US-4410867-\$ or US-5850167-\$ or US-5140403-\$ or US-6088462-\$ or US-6110598-\$ or US-5281554-\$ or US-6375312-\$ or US-5714268-\$ or US-6191031-\$ or US-6154105-\$).did. or (JP-04186815-\$).did.) and (tungsten with titanium)	USPAT; JPO; DERWENT	2004/01/15 09:40
-	666	saw and (tungsten with titanium)	USPAT; JPO; DERWENT	2004/01/15 09:40
-	0	saw and (tungsten with titanium) with bilayer	USPAT; JPO; DERWENT	2004/01/15 09:41
-	0	saw and ((tungsten with titanium) with bilayer)	USPAT; JPO; DERWENT	2004/01/15 09:41
-	0	saw and ((tungsten with titanium) with bi-layer)	USPAT; JPO; DERWENT	2004/01/15 09:41

-	0	saw and ((tungsten same titanium) with bi-layer)	USPAT; JPO; DERWENT	2004/01/15 09:41
-	728	saw and (tungsten same titanium)	USPAT; JPO; DERWENT	2004/01/15 09:41
-	257	saw and ((tungsten same titanium) with tantalum)	USPAT; JPO; DERWENT	2004/01/15 09:42
-	255	saw and ((tungsten with titanium) with tantalum)	USPAT; JPO; DERWENT	2004/01/15 09:45
-	11	saw and ((tungsten with titanium) with tantalum with piezoelectric)	USPAT; JPO; DERWENT	2004/01/15 09:45